

# PATENT ABSTRACTS OF JAPAN

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## (30)Priority

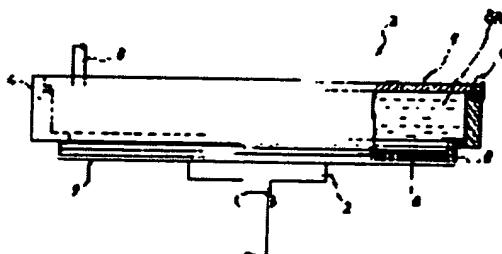
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## (54) LIQUID SUPPLY NOZZLE

### (57)Abstract:

**PURPOSE:** To provide a liquid supplying nozzle which supplies the prescribed liquid rapidly in a short time without giving impact a subject to be processed and without generating bubbles and that efficiently processes with a small quantity of liquid.

**CONSTITUTION:** A liquid supplying nozzle 3 provided on the top of a spin chuck 2 which supports a semiconductor wafer 1 is provided with a short container-shaped liquid storing part 4 and many fine holes 6 at the bottom of the liquid storing part 4. Then, the prescribed developer is supplied into the liquid storing part 4 at the prescribed pressure from a developer supplying pipe 8 and the developer is supplied to the semiconductor wafer 1 by bleeding the developer



from the many fine holes 6.

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